



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)
Hongyong ZHANG et al.) Group Art Unit: 2823
Application No. 08/811,742)
Filed: March 6, 1997) Examiner: K. NGUYEN
For: SEMICONDUCTOR DEVICE AND)
FABRICATION METHOD OF THE)
SAME) Confirmation No.: 1505

RESPONSE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following is presented in response to the Office Action, mailed October 28, 2003, in connection with the above-captioned patent application.

Claims 49-66 and 85-120 are currently pending in the application with claims 85-120 being subject to examination; while claims 49-66 have been withdrawn from consideration as being directed to a non-elected invention.

Referring now to the detailed Office Action, the Applicants respectfully traverse each of the Examiner's rejections of:

Claims 85-87, 90-93, 96-99, 102-105, 108-111, 114-117 and 120, under 35 U.S.C. §102(b), as being anticipated by the teachings of Oka (JP '915), and

Claims 88, 89, 94, 95, 100, 101, 106, 107, 112, 113, 118 and 119, under 35 U.S.C. §103(a), as being obvious in view of the combination of teachings of Oka (JP '915) and the Kuznetsov (Inst. Phys. Conf.) article.

Each newly added independent claim recites a method for manufacturing a semiconductor device comprising the steps of:

-forming a semiconductor film over a substrate,
-disposing a crystallizing promoting material in contact with a selected portion of the semiconductor film,